



IEEE SW Test Workshop
Semiconductor Wafer Test Workshop

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Rapid Diagnostics Using a Prober Based PCA



Tools for Verifying Connections

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Motivation

- **Experienced the challenges of building advanced memory probe cards**
- **How do you ensure your probe card works in production?**
 - Cards in production deflect differently than PCAs
 - Testing at multiple temperatures is required
 - Intermittent connections can not be detected
 - Life testing with relays does not work
- **Test solutions get expensive**
 - Probe counts - 60K+, embedded ICs, card sizes - >480 mm
 - Need convoluted test flow with custom developed tools
- **Need real time and comprehensive diagnostic tools**
- **There has to be a simpler solution**



Challenges

- **Probe cards can generate >200Kg force & every test cell can deflect differently**
 - Deflection contributors
 - Prober chuck and head plate
 - Probe cards and their attachment to head plates
 - ATE test head weight
 - Temperature distortion (-45 to +200°C)
- **Significantly reduce the cost of test**
- **How do you test for Cres and electrical planarity with ICs in the way?**



Objectives / Implementation

- **Minimize deflection differences of test cells**
 - Mount switch electronics on probe card in target prober
 - Use ATE suppliers interface kits to attach to head plate
 - Use manipulator to support electronics & replicate load
 - Perform tests at all required temperatures
 - Measure tip positions using scrub marks on blank wafer
- **Reduce cost of test**
 - Faster parallel bussed pin testing
 - Streamline the test flow – keep on one tool
 - Minimal cabling and connectors
 - Scrub mark damage to replace force measurement
- **Test through embedded ICS**
 - Any channel can be a logic control channel



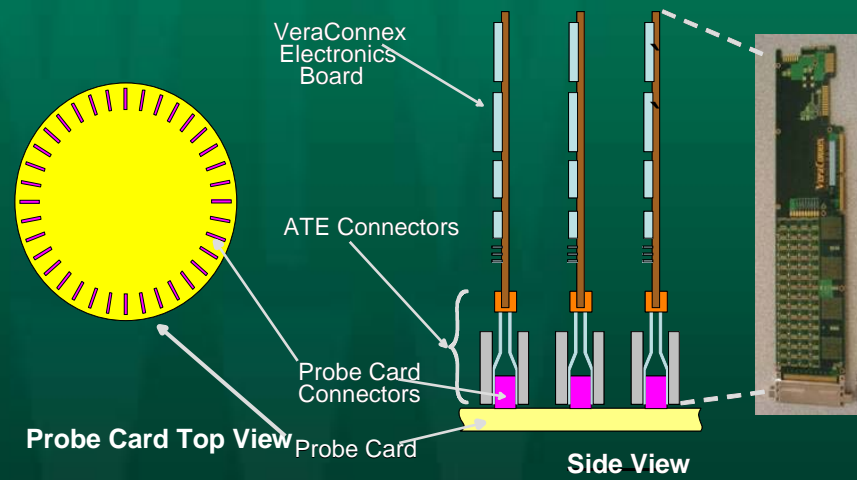
Approach

- **First target: ATE with large installed base**
 - Advantest T5375: 96 ZIF connectors, 440 mm
- **Criteria**
 - True 4 - point measurements
 - Control digital ICs
 - High performance: intermittent & life time testing
 - Hot switching & stable \Rightarrow solid state switches
 - Measure passives and relays
 - Scalable architecture: start at 65,536 channels
 - Thorough self-test: configuration and communication
 - Confocal microscope: location & damage = force



Electronics Hardware

- Manipulator to support pin electronics and match load



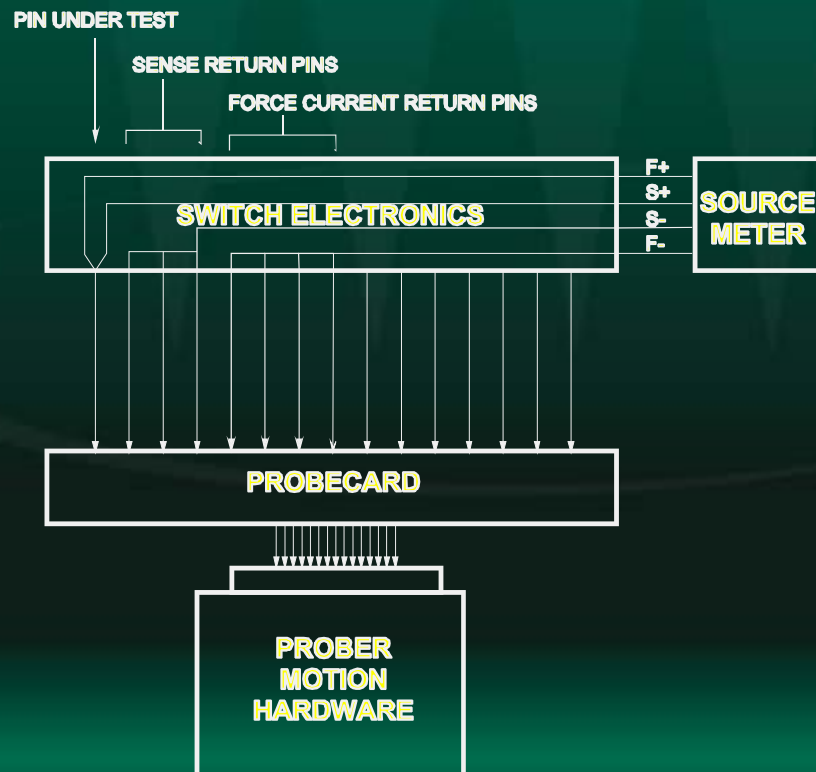
- Prototype: Shown directly mounted on head plate of EG prober



Prototype on EG Prober

Cres Testing: Signal Probes

- **4-wire resistance measurement of each probe using probe card**
 - Use prober to raise blank metalized wafer in contact with all probes
 - Connect force F+ and sense S+ rails from measurement unit to selected probe
 - Connect force F- and sense S- from measurement unit to several near by probes
 - Voltage across F+ to F- limited to $< 50\text{mv}$ to not burn through interface layers



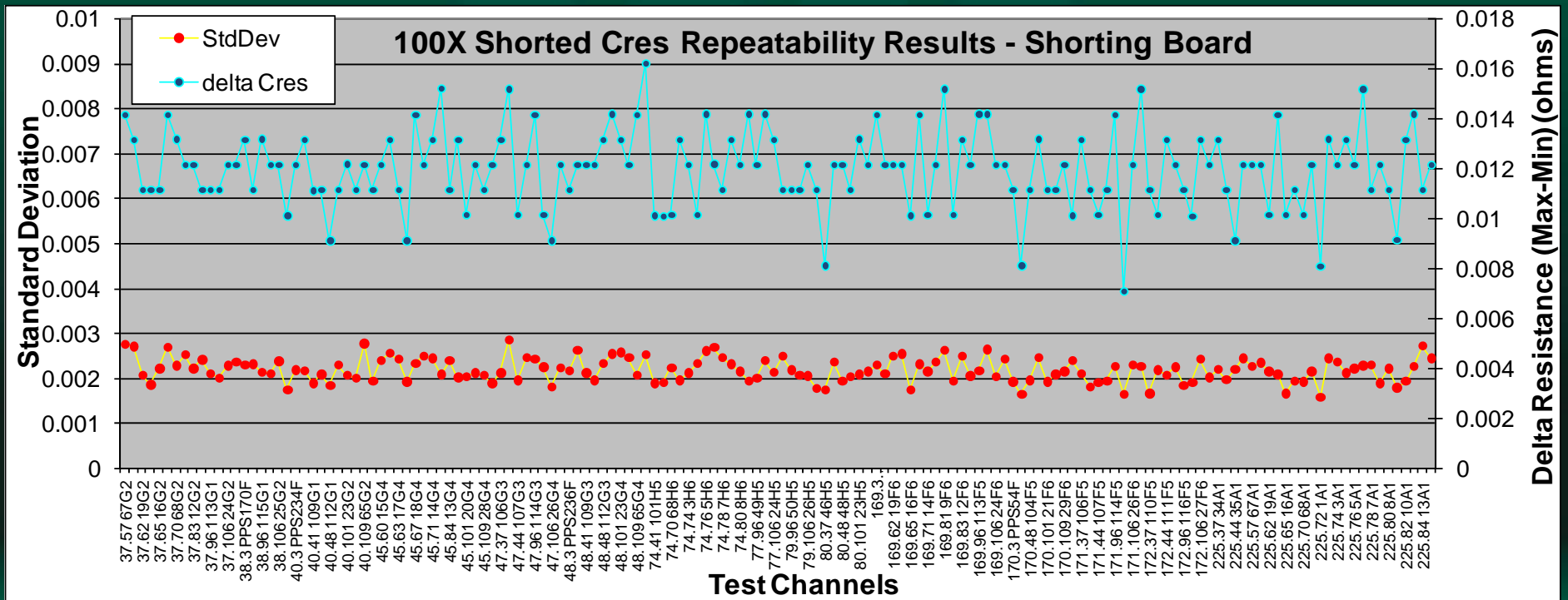
Performance Verification

- **Use system to analyze a 64 site LM4 probe card to evaluate tool effectiveness in diagnosing problems**
 - Electrical Planarity (on Au and Al wafers)
 - Cres on 100 touchdowns to Au and Al wafer
 - Leakage
- **Verify measurement speed**
 - More than 300 Cres tests per second
(Data+Reports for presentation in minutes)
 - Immediate data analysis and capture of images from electrical results

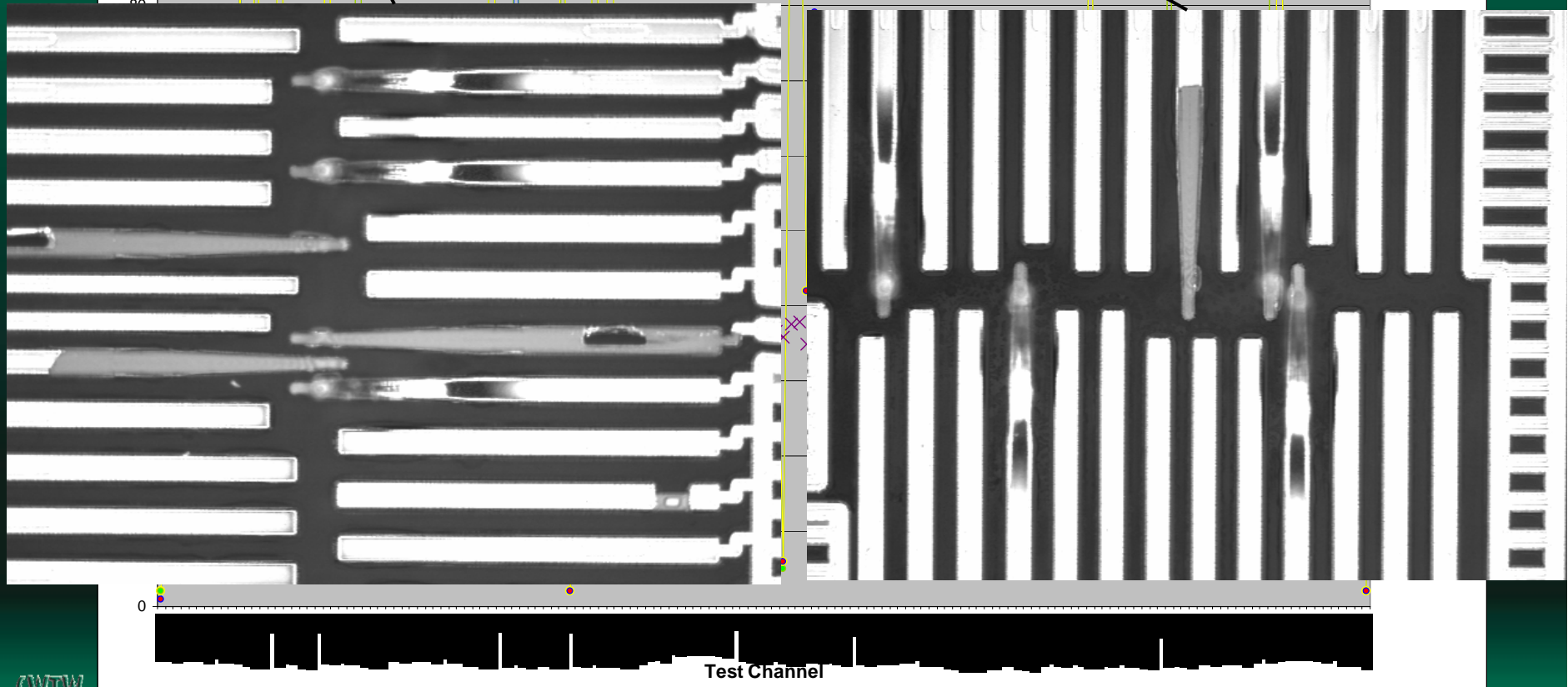
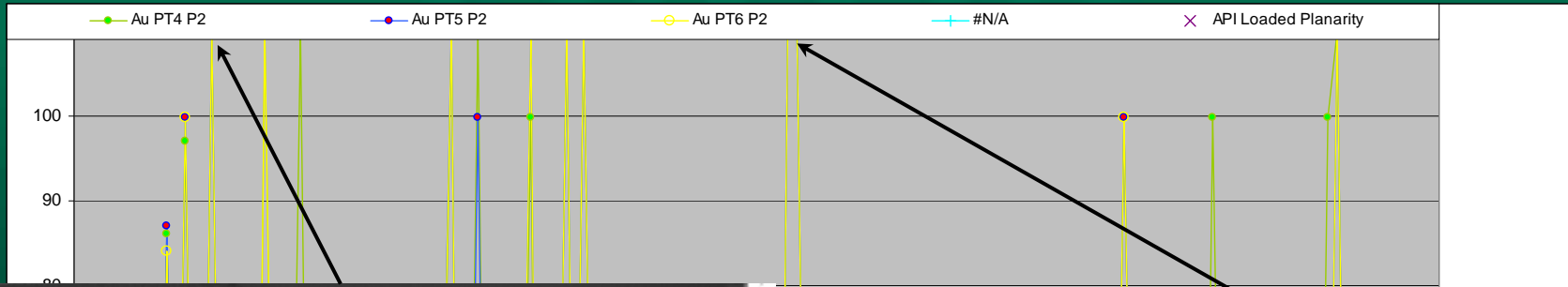


Resistance Repeatability

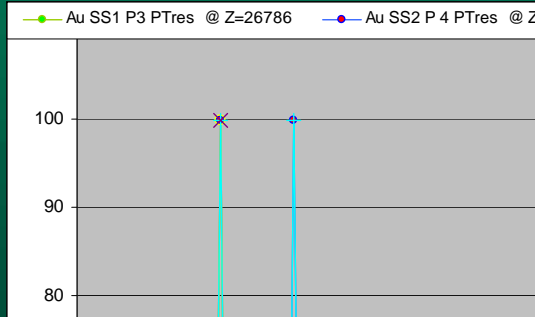
- **Pin Card Measurements with shorting board**
 - 100 Measurements are consistent to within 16 mohms
 - Values include: Shorting resistance +Traces + Connector



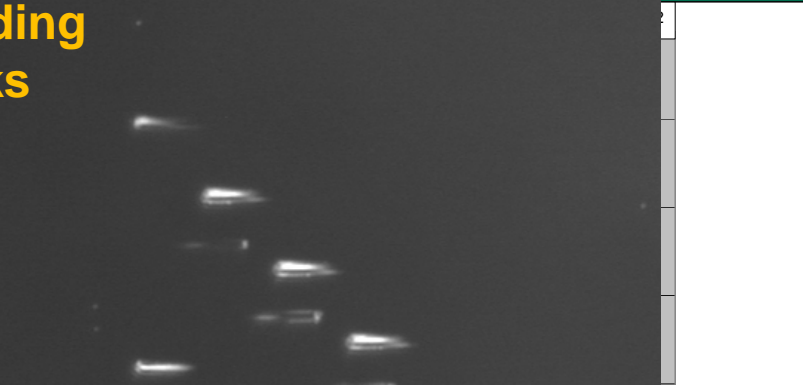
3X Planarity Results on Au Wafer



Stepping Cres on Au Wafer (100um OD from 1st touch)



**Corresponding
Scrub Marks**



Hi-Res DPS Camera [F9: change Resolution]

**Positions with
Fluctuating
Cres**

Location:
Z Location:

Hi-Res DPS Camera [F9: change Resolution]

**After 50
steps on
Probe
Clean™ @
50um OD**

Z:24420.0 (Jog)
Location: -203.913 4.123
PrbCard Z: 12092.4
Z Location: 24.420

[cr: Text mode]
[S: start measure]
[E: end measure]

[7:+0bli] [9:+Coax]
[1:-0bli] [3:-Coax]

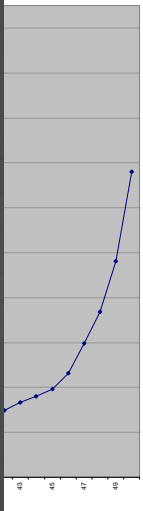
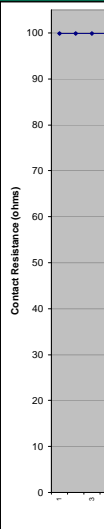
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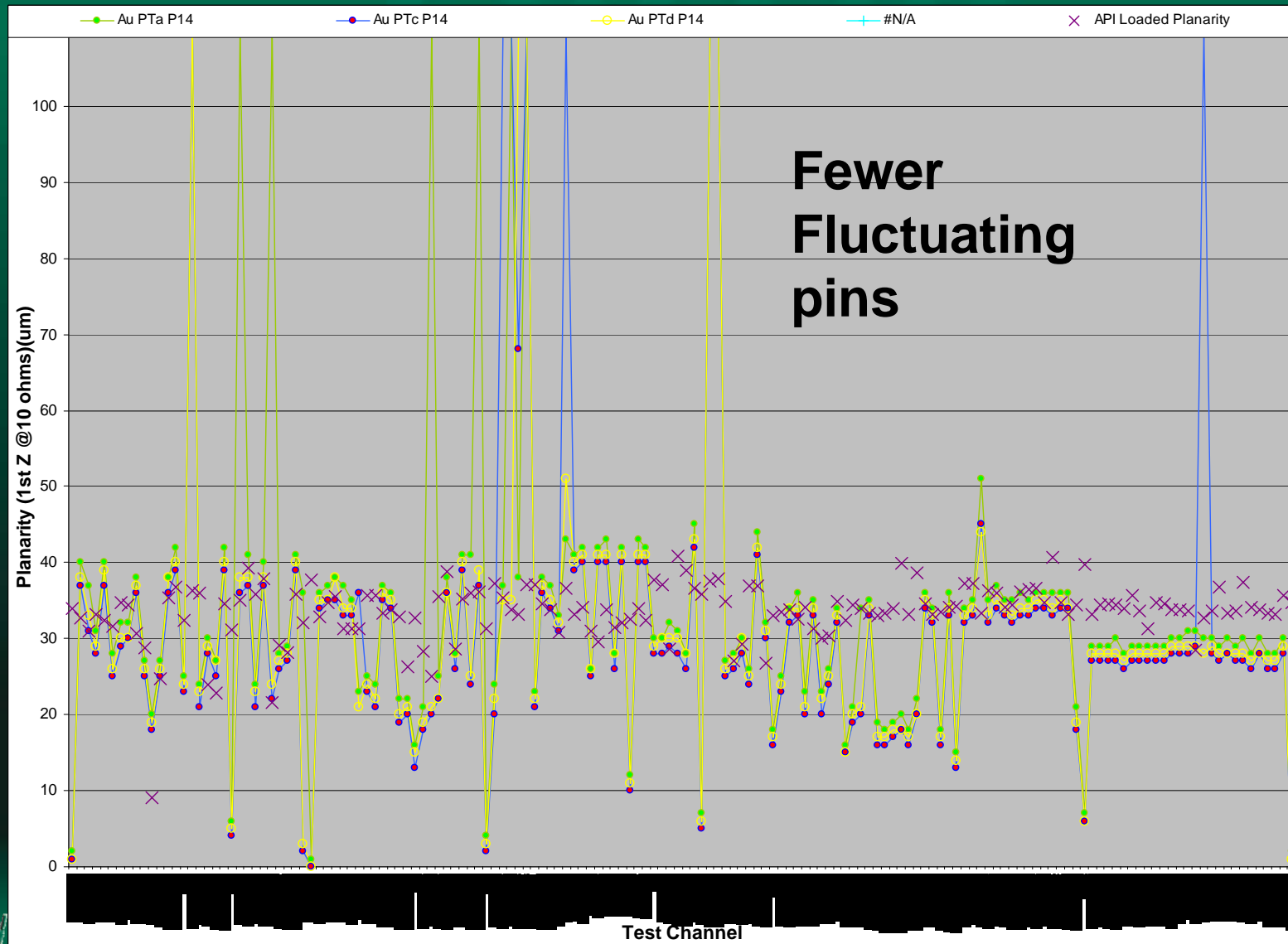




After Probe Clean™ + 50 Steps on WC + Probe Clean™

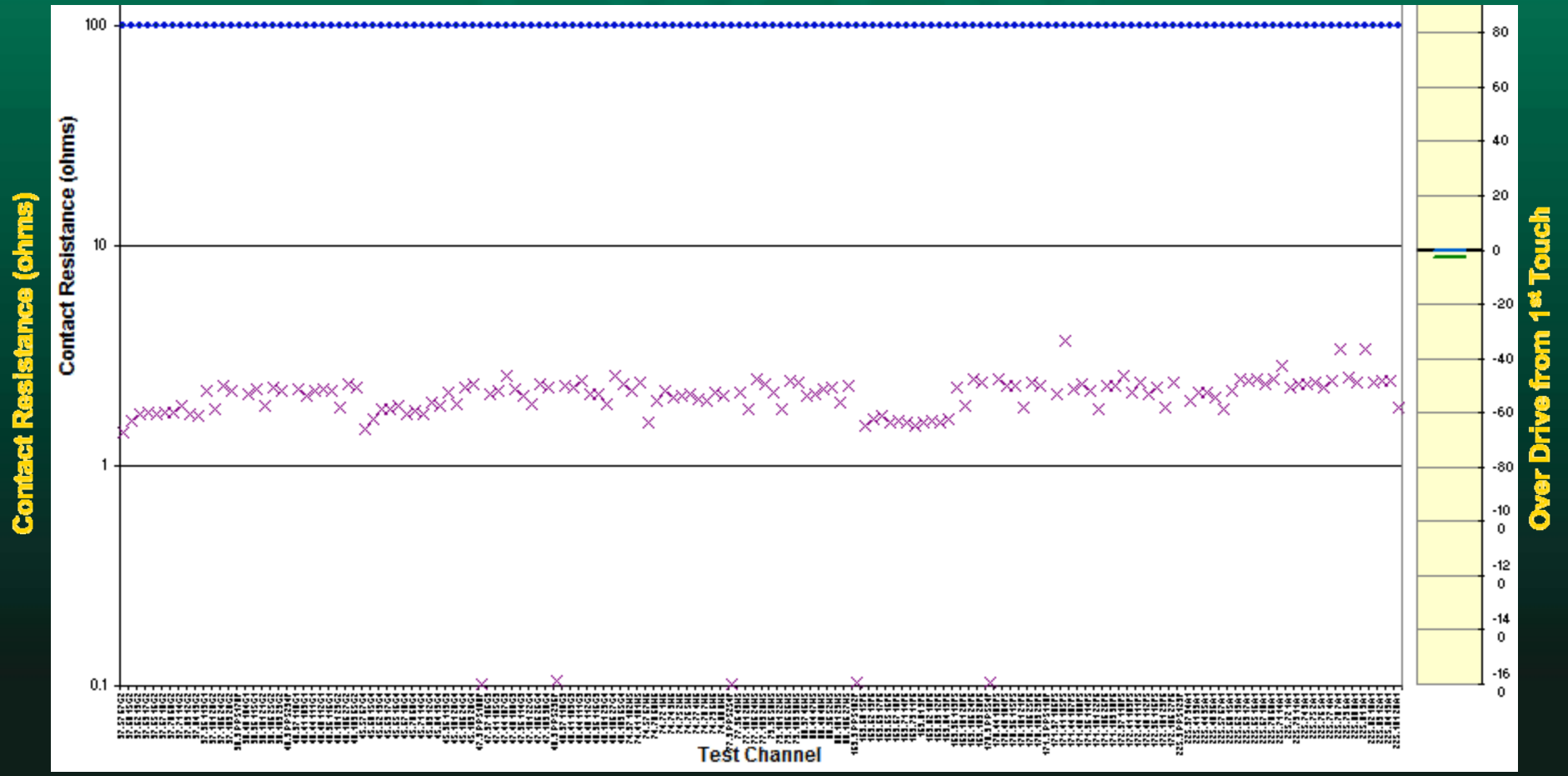


3X Planarity on Au Wafer after clean



Animation of Contact Resistance During Planarity Test

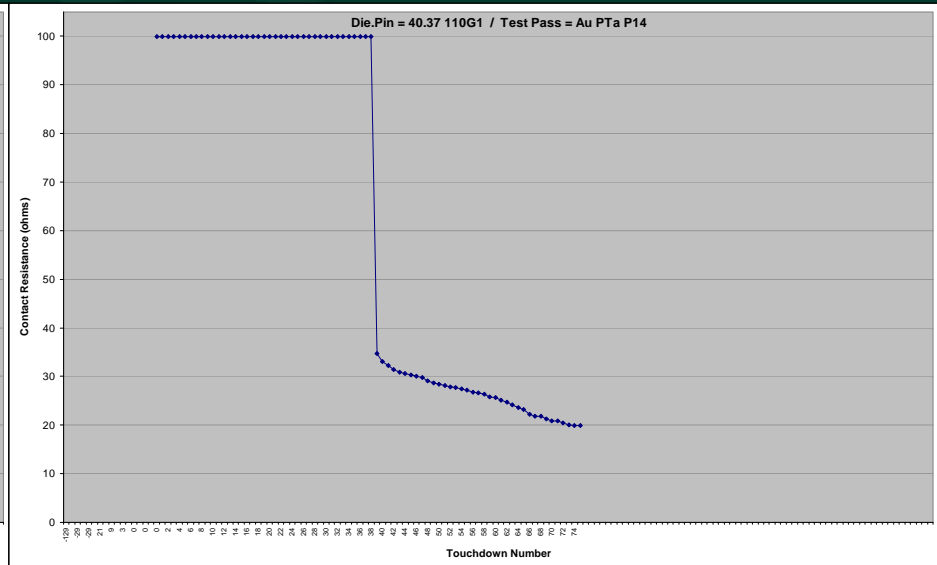
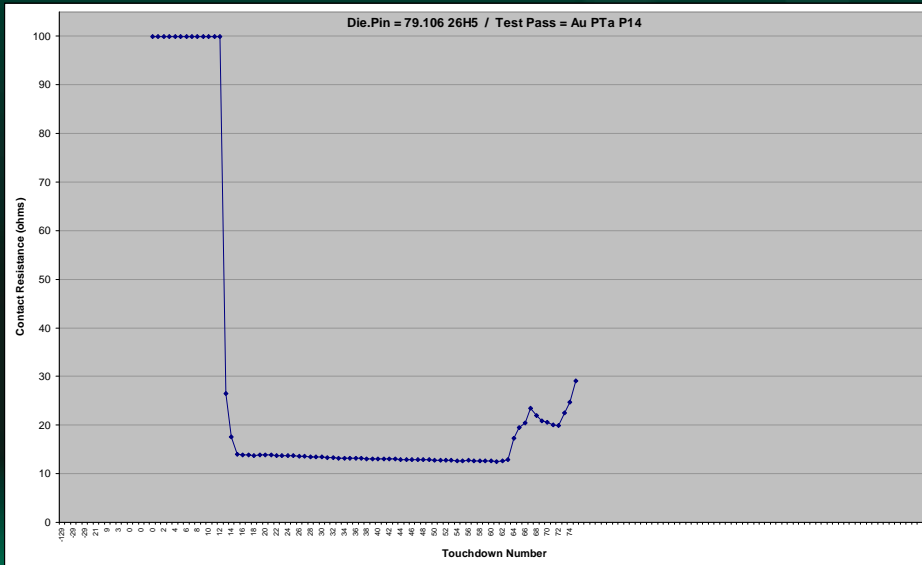
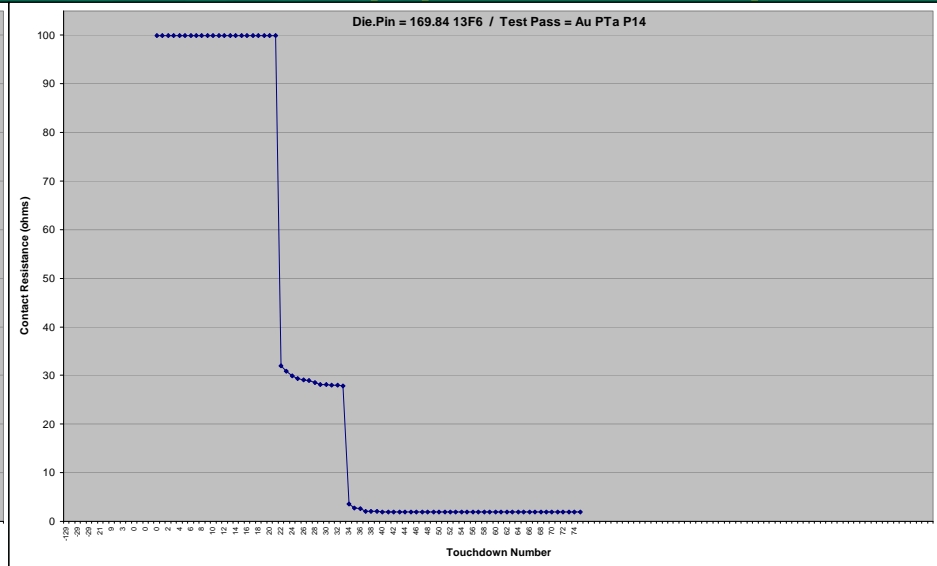
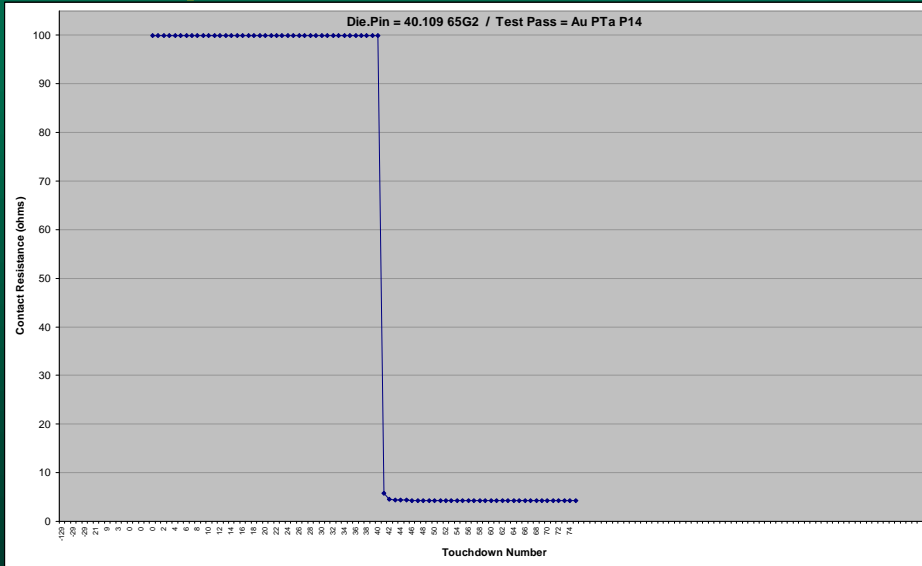
● Before Cleaning ● After Cleaning



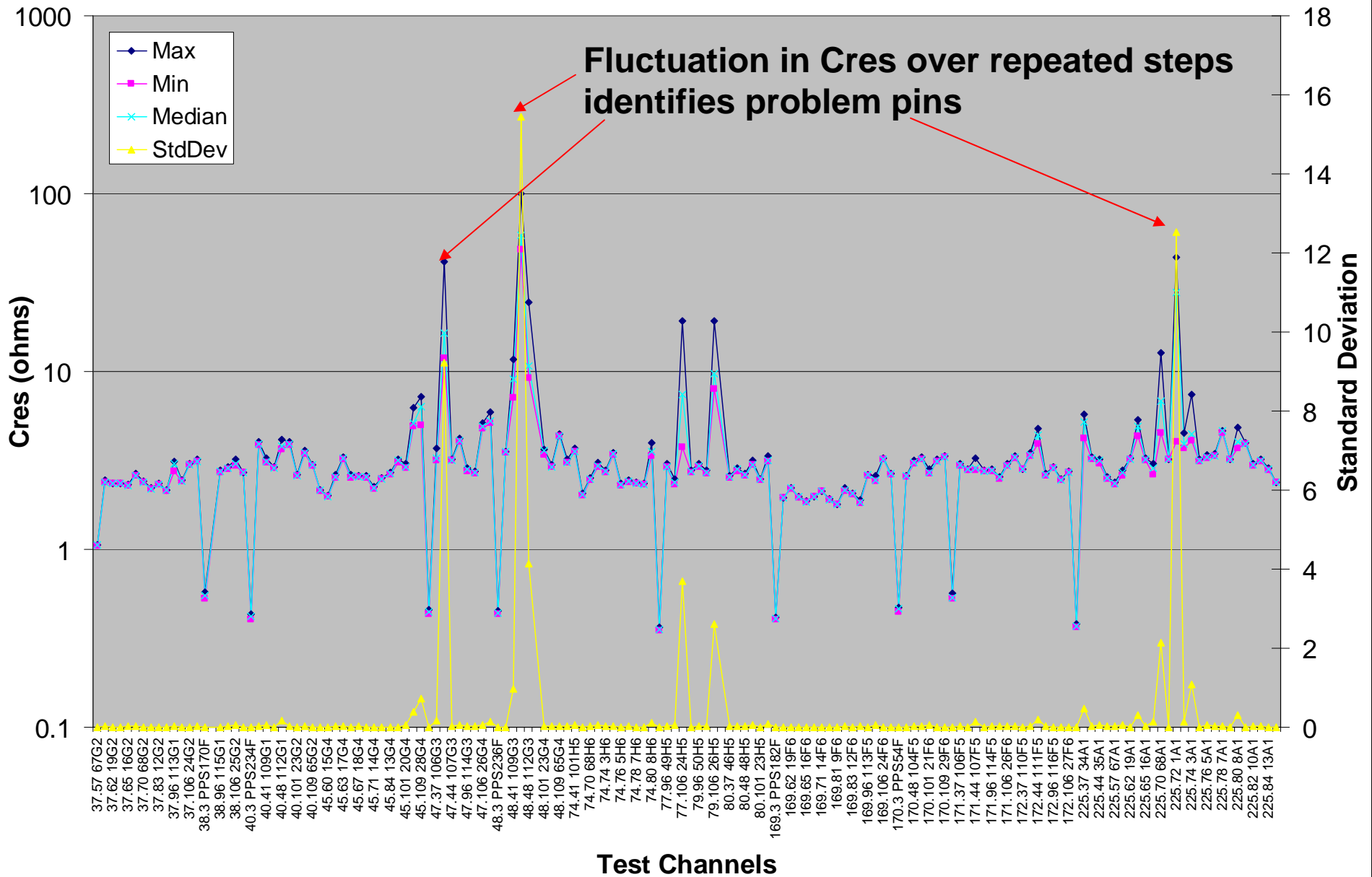
← 154 Test Channels →



Individual Pin Cres During Planarity Test (Au Wafer @ 75um OD after 1st touch) (Post clean)

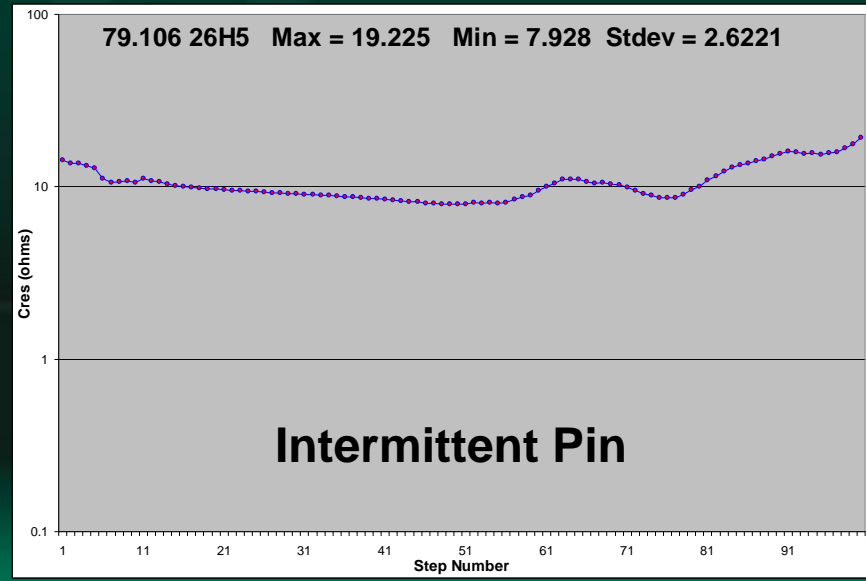
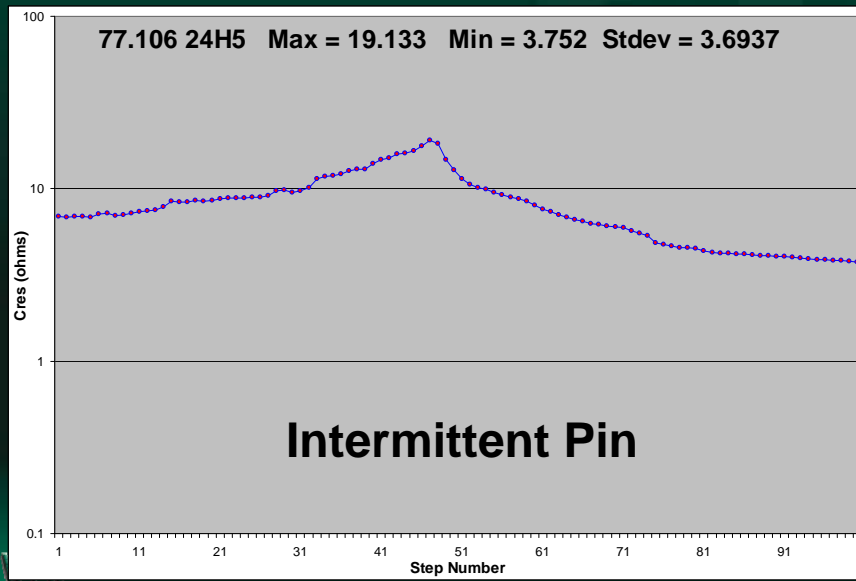
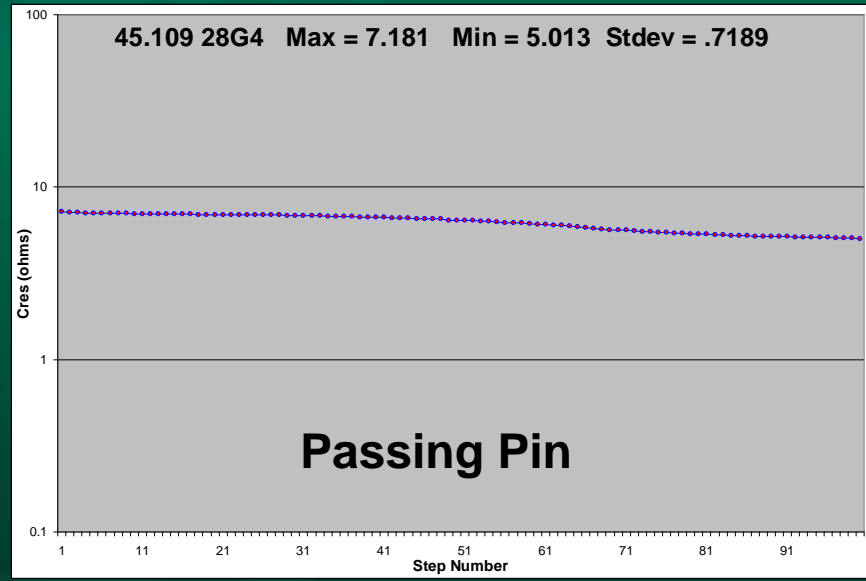
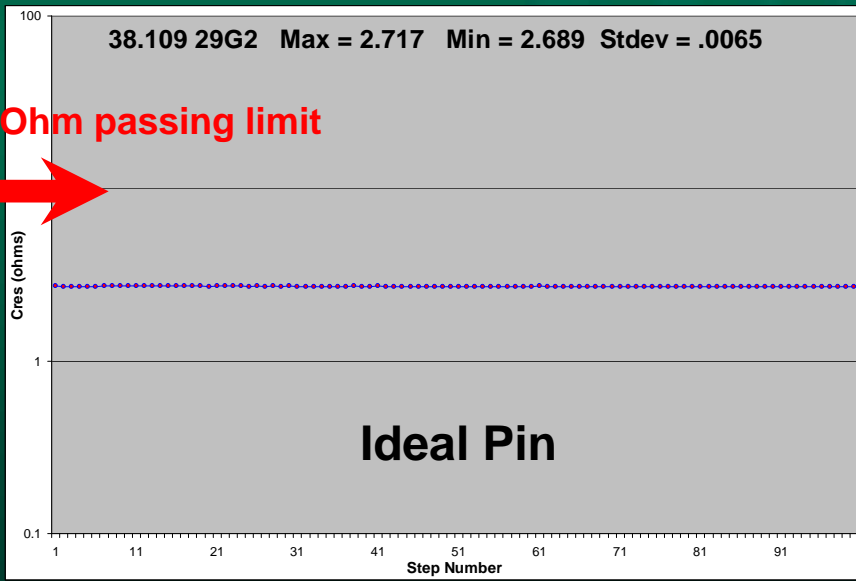


100 Step Repeatability Results - No stepping (Pos 1) (50um OD on Au6)

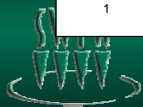
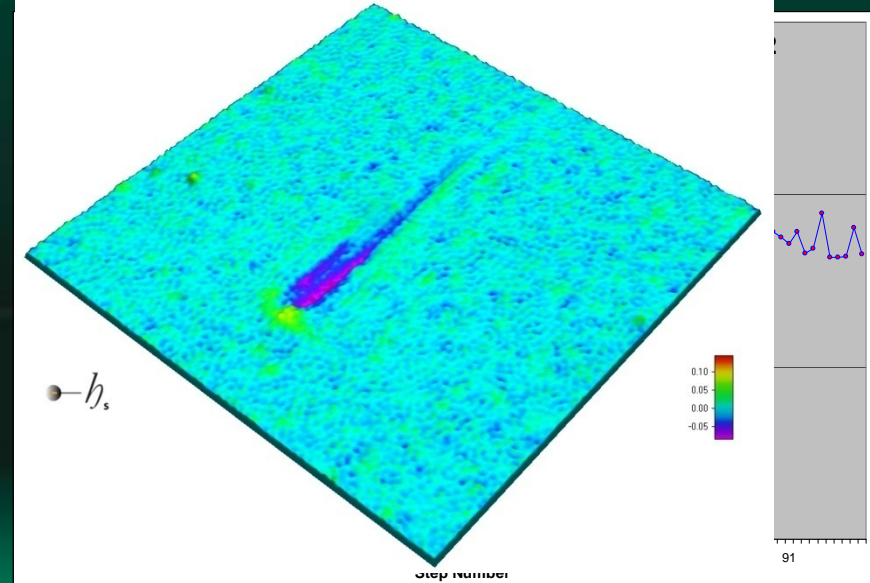
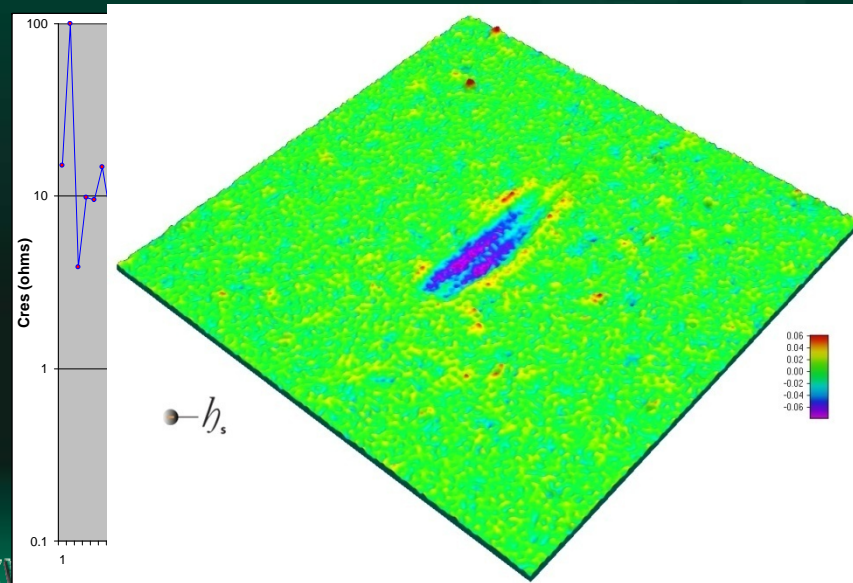
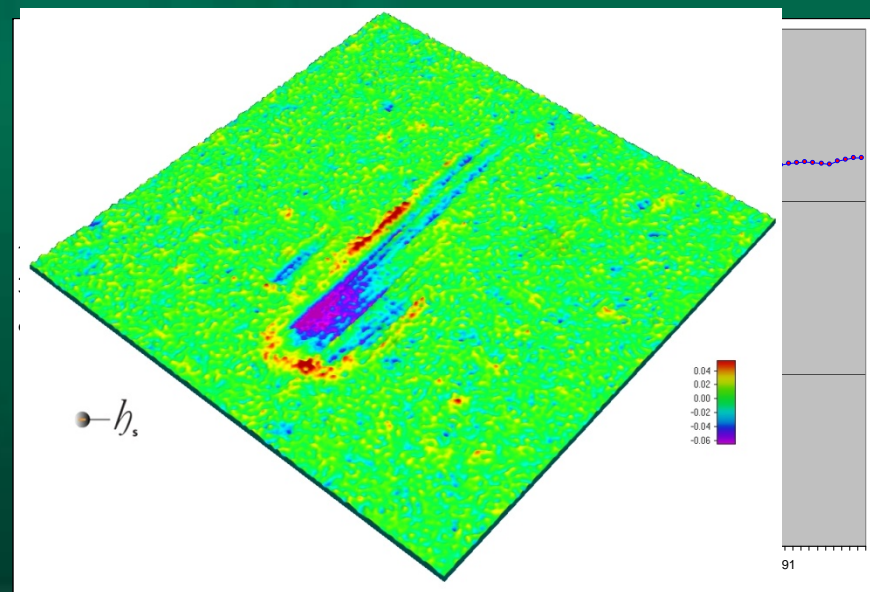
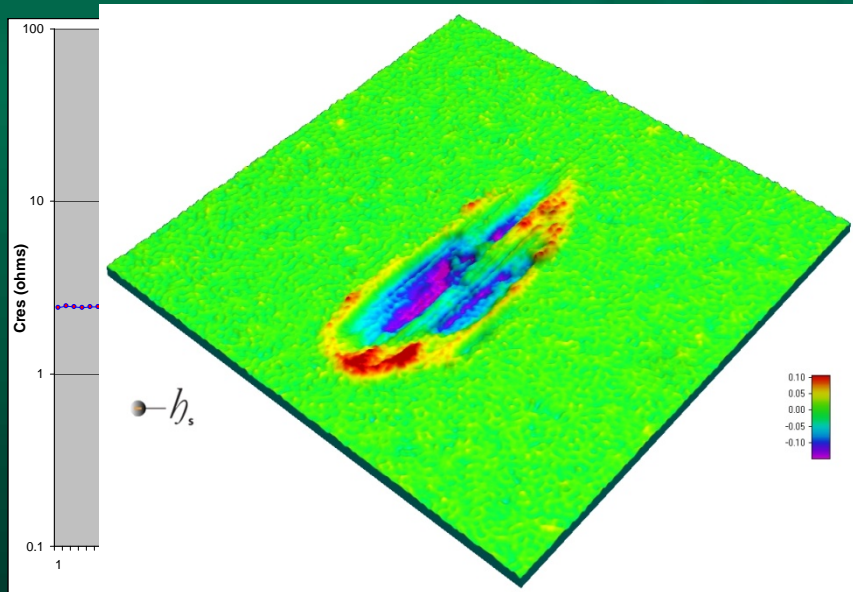


Per Pin Cres Signature over 100 Steps on Au

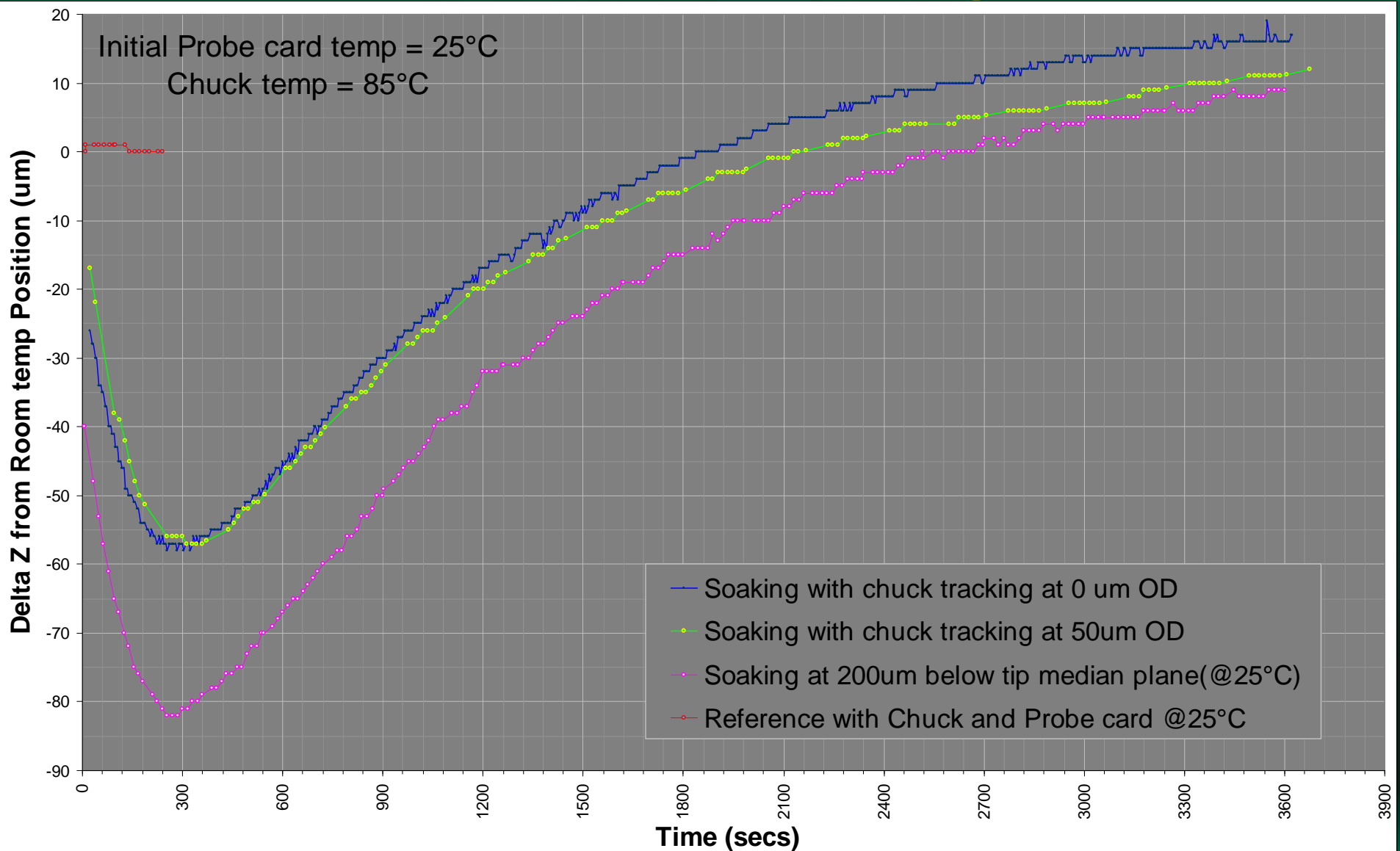
10 Ohm passing limit



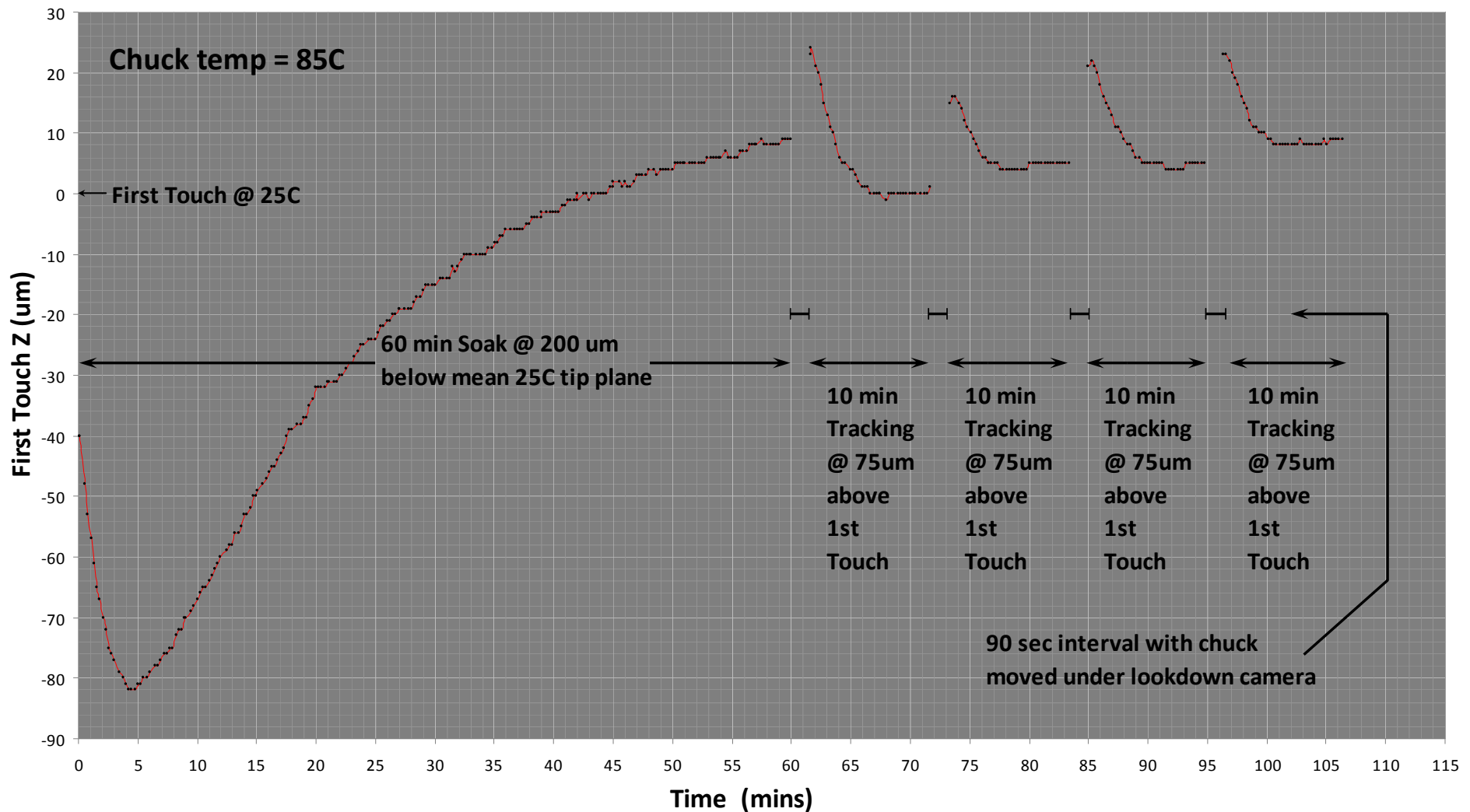
Per Pin Cres signature over 100 Steps on AI



First Touch Z Sampled During 1 hr Soak



Dynamic First-Touch Z Profiling



Results

- **Demonstrated that the system can collect data in minutes and provide immediate analysis**
- **Fast electronics integrated into prober opens up new methods in diagnosing problems**
 - Fast Cres measurements enable collection of individual pin signatures
 - Can identify unique problems despite passing Cres
 - Intermittent Cres can be identified
 - Dynamic planarity behavior of probe card can be observed
 - Integrated real time data analysis help correlate measurements to problem pins



Follow-On Work

- **Investigate other signatures**
 - Scrub
- **Correlation of pin signature to**
 - Probe card life
 - Product die test yield



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